



Response Under 37 C.F.R. § 1.116  
Expedited Procedure  
Examining Group 2855

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Gotkis et al.

Application No: 10/671,978

Filed: September 26, 2003

For: METHOD AND APPARATUS FOR WAFER  
MECHANICAL STRESS MONITORING AND WAFER  
THERMAL STRESS MONITORING

Attorney Docket No: LAM2P438

Examiner: DAVIS, O.

Group Art Unit: 2855

Date: January 13, 2006

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on January 13, 2006.

Signed:   
Michael L. Gencarella

Commissioner for Patents  
Mail Stop AF  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application. The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE	OR	LARGE RATE FEE	ENTITY
TOTAL CLAIMS	13	20	00	X25 = \$	OR	X50 = \$	
INDEP CLAIMS	03	03	00	X100 = \$	OR	X200 = \$	
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$180		X360	\$
			TOTAL	\$		\$	



Applicant(s) hereby petition for a one-month extension of time to respond to the outstanding Office Action.



Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805 (Order No. ).




Enclosed is Check No. 15634 in the amount of \$120.00 to cover the additional extension of time fees.



If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P438). A copy of this sheet is enclosed.

Respectfully submitted,  
MARTINE PENILLA & GENCARELLA, LLP

  
Michael L. Gencarella, Esq.  
Registration No. 44,703

710 Lakeway Drive, Suite 200  
Sunnyvale, CA 94085  
Telephone: (408) 774-6921  
Customer Number 25920



Response Under 37 C.F.R. § 1.116  
Expedited Procedure  
Examining Group 2855

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	)	Attorney Docket No: LAM2P438
	)	
Gotkis et al.	)	Examiner: DAVIS, O.
	)	
Application No: 10/671,978	)	Group Art Unit: 2855
	)	
Filed: September 26, 2003	)	Date: January 13, 2006
	)	
For: METHOD AND APPARATUS FOR WAFER	)	
MECHANICAL STRESS MONITORING AND	)	
<u>WAFER THERMAL STRESS MONITORING</u>	)	

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450, on January 13, 2006.

Signed:

  
Michael L. Gencarella

REQUEST FOR RECONSIDERATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313

Dear Sir:

Applicants submit this amendment in response to the Office action dated September 13, 2005. A one month extension of time is hereby petitioned for to extend the time for response to January 13, 2006. Please enter the following remarks in the above identified application:

The claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

01/19/2006 BABRAHA1 00000001 10671978

01 FC:1251

120.00 OP